

Attorney Docket No. 59521 (48229)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Hiroyuki Shimada

EXAMINER: Chen Kin Chan

U.S.S.N.:

10/678,994

GROUP ART UNIT: 1765

FILED:

October 3, 2003

CONFIRMATION NO.: 8918

FOR: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE INCLUDING ETCHING A CONDUCTIVE LAYER BY USING A GAS

INCLUDING SiCl4 and NF 3

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Sir:

AMENDMENT AFTER FINAL

In response to the Office Action dated October 31, 2005, Applicant submits the following amendment.

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